

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**DOCKET NO.
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SHTEIN et al.FILING DATE
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1762**U. S. PATENT DOCUMENTS**

EXAMINER INITIAL	DOCUMENT NUMBER	PUBLICATION DATE	NAME	CLASS	SUBCLASS	FILING DATE

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						Yes	No
	WO 02/087787	November 7, 2002	PCT			X	
	WO 03/020999	March 13, 2003	PCT			X	

NON PATENT LITERATURE DOCUMENTS

EXAMINER INITIAL		AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
		Shtein et al., "Direct mask-free patterning of molecular organic semiconductors using organic vapor jet printing", Journal of Applied Physics, Volume 96, Number 8, pp. 4500-4507, October 15, 2004.

EXAMINER	/David Turocy/	DATE CONSIDERED	03/22/2010
EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.			